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#### D T C Allcock H A Janacek J A Sherman T P Harty D N Stacey A M Steane The Oxford planar ion trap project

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# Oxford Fabrication - New J. Phys. Allcock et. al. (2010)

Planar traps based on a simple metal patterned substrate have recently been demonstrated at NIST [1] and MIT [2] with promisingly low heating rates measured. This type of trap is inherently scalable, and manufacturable in-house on short time scales allowing rapid testing and development of electrode geometries. We have fabricated a trap with a geometry similar to the proposed Sandia Mk2 (see below) as a proof of principle. [1] Seidelin et al. PRL 96, 253003 (2006), [2] Labaziewicz et al. PRL 100, 013001 (2008)

|5|3

### **Fabrication Process**

Quartz substrate with gold electrodes. Electrodes electroplated over silver seed layer. Based on MIT method. See thesis of J. Labaziewicz.





Trap under vacuum (right). Imaging is through the front window which is conductive (ITO coating) to prevent charging. The laser beams pass through the side windows and pass parallel to the trap's surface.

| Ion-Surface Distance     | 150   |
|--------------------------|-------|
| Rf Frequency             | 25.8  |
| Rf Voltage Amplitude     | 112   |
| Pseudopotential Depth    | 47 to |
| Radial Secular Frequency | 2.01  |
| Axial Secular Frequency  | 300   |
| Ion Lifetime (typical)   | 5 mi  |
| I                        |       |

Our trap (far left) is of a '6-wire' design. The split central control electrode (CCE) allows a static quadrupole (above, centre) to be applied at the ion's location with the dc electrodes. This tilts the radial normal modes so that the laser cooling



| Ion-Surface Distance     | 150 µm             |
|--------------------------|--------------------|
| Rf Frequency             | 25.8 MHz           |
| Rf Voltage Amplitude     | 112 to 223 V       |
| Pseudopotential Depth    | 47 to 188 meV      |
| Radial Secular Frequency | 2.0 to 4.0 MHz     |
| Axial Secular Frequency  | 300 kHz to 1.2 MHz |
| Ion Lifetime (typical)   | 5 min              |
|                          |                    |

A typical rf correlation scan (inset,

left). By applying a compensation

field and monitoring the correlation

scan we can null any micromotion

 $P_{1/2}$   $\tau = 7.1 \text{ns}$ 

 $S_{1/2}$ 

 $D_{3/2}$ 

0.9





D M Lucas

wire-bonded into a CPGA carrier (top). The carrier also includes single-layer 820pF filter capacitors for the dc electrodes. Three calcium ions in the trap (above right).  $P_{3/2} \ \tau = 6.9 \text{ns}$  $P_{1/2}$  $D_{5/2}$  $D_{3/2}$  $\tau = 1.17 s$  $\tau = 1.20 s$ The low-lying D-states in Ca<sup>+</sup> complicate analysis of this experiment if we repump out of them via the  $P_{1/2}$  state due to coherent dark resonance effects. Instead we use the modified scheme above. As no laser connects the boxed levels to our fluorescing transition we can treat our system as quasi-two-level (see -10 Lorentzian fit, left).

Vias (W)

10-20 µm SiO<sub>2</sub>

**Cross-under** 

Insulating

dielectric



beams couple efficiently to them (left).

(left).

### - $5 \mu m$

# Heating Rates

We measure the motional heating rate of the trap using a Doppler re-cool method [4]. The ion is allowed to heat for ' second and then the Doppler cooling laser is switched back on. Analysis of the ion's fluorescence as it cools back down allows us to determine its temperature. A typical re-cool curve is shown inset below.

[4] Wesenberg et al. PRA 76, 53416 (1998)



The electric field noise density  $S_E$  is comparable to other traps of this size and corresponds to  $\sim 50$  phonons of heating per ms at 500 kHz axial frequency. Before adequate heating rate data was taken an rf fault caused arcing which damaged the surface quality and lowered the breakdown voltage to around 150 V. We see clear evidence of electron emission from the increase in background photon counts at higher rf.

**Designed oxide** 

undercut

Device thru-hole for

ion loading and optical

access

100µm wide slot and all electrode

The ion sits directly above the

Trap rf drive causes driven micromotion when ion is displaced from rf null by stray fields. Doppler shifts cause correlation between 397nm ion fluorescence and trap rf which can be used for micromotion detection [3]. Beams in plane of trap cannot detect micromotion out-of-plane so we reflect 866nm repumper off trap (left). In regime of high repumper intensity the Doppler shifts of the repumper couple to the P-population and modulate the



fluorescence [3] Berkeland et al. J App. Phys. 83, 5025 (1998)

-20



**Micromotion Compensation** 

150 *µ*m

Repumper

By solving the Bloch equations for the steady state under repump laser modulation we can predict the optimal laser parameters. This contour plot (below right) shows the sensitivity to micromotion for different repumper laser intensities and cooling laser detunings as a fraction of the fluorescence rate. For all points the optimal repumper detuning is 10-20 MHz to the red of the cooling laser. The relative sensitivity drops off

linearly with cooling laser intensity Ic but we set Ic to 1.5 saturations to achieve a good absolute sensitivity. The graphs to the left show a good experimental fit to our model.

Using this method we are able to compensate stray fields out of the plane to within 3 V/m compared to 1 V/m in the plane (peak ion velocities of 0.3 and 0.1 m/s

Plan view

Doppler cooling



respectively). We note a drift rate of approximately 10 V/m per hour, but no noticeable change on loading.



# Sandia Fabrication

Fabrication completed at Sandia National Laboratories (M. Blain & D. Stick) funded by iARPA. Design and testing input from Oxford and Innsbruck (W. Hänsel).



Reliable trapping demonstrated at both Sandia (see arXiv:1008.0990) and Oxford. Heating rate measurements awaiting modified trap with better rf grounding on centre control electrodes. This is to reduce rf pickup which is leading to uncompensatable micromotion.



## **Features**

- Ion 'sees' no dielectric or exposed semiconductor.
- Trap can be evaporatively coated with different metals to investigate effects of surface composition on ion heating.

Trap electrodes (AI)

Buried SiO<sub>2</sub>

gaps are 7µm.

- Split central electrode allows rotation of trap principle axes for efficient laser cooling even in a symmetric design.

## **Future Developments**

- Slot designed to accommodate pre-aligned package of diffractive optics and fibres for laser delivery and fluorescence collection.

Top Si

**Substrate Si** 

- Integration of passive filters into the trap
- Integration of filters into the trap structure is possible with this fabrication technology.





Disadvantages - Current densities approach limits imposed by heat dissipation - Gate speed will be fairly slow (~500us) for trap this size. - Crosstalk will be an issue in larger arrays.

Future developments - Single qubit gates with Raman lasers.

- Single ion addressing through ion separation. - <sup>88</sup>Sr<sup>+</sup> sympathetic cooling.

Prototype multiplexer board (above) for combining microwave gate drive, rf trap drive and dc bias. Board designed in Microwave Office.

RF

in

50 Ohm coplanar waveguide

Transmission line coupling elements. Electrically equivalent to SMA connectors series capacitors at 3.2 GHz but allows RF and DC connection.

http://www.physics.ox.ac.uk/users/iontrap/ d.allcock@physics.ox.ac.uk Department of Physics, Clarendon Laboratory, Parks Road, Oxford, OX1 3PU, United Kingdom

Gold electrodes on sapphire

for good heat conductivity.

substrate with aluminium base





**Microtrap**•